positions of the remaining hydrogen atoms were calculated (P-C-H and $H-C-H = 109.5^{\circ}$). Refinement of all non-hydrogen atoms anisotropically resulted in $R_w = 0.068$; this small improvement (for 85 extra variables) combined with the large deviations in the anisotropic thermal parameters indicated that the data were not sufficiently accurate to warrant this degree of refinement. At this point a correction for the 1.5% decay of the three standard reflections was applied, but as expected, the effect was small. Final refinement with anisotropic thermal parameters for tungsten, antimony, and phosphorus only and recalculation of the hydrogen atom positions gave the residuals in Table X. The largest peaks on the final difference map were all due to heavy-atom noise, being randomly oriented about the tungsten and antimony atoms at distances of 1.01-1.21 and 0.96-1.10 Å, respectively. Finally, there is one relatively short intermolecular contact of 2.30 Å between F(6) and H(10)(the hydrogen atom on C(10)).

Structure Determination of 3c. Crystals were obtained by layering hexanes onto a cold solution of 3c in CH₂Cl₂ and allowing the mixture to stand at -40 °C overnight. The successful solution of the structure ultimately justified the initial assumption of space group $P\overline{1}$. A 1.0% decay in the intensities of the three standard reflections was observed over the course of the data collection, but no correction was applied. Positions and isotropic thermal parameters for the 35 non-hydrogen atoms refined as above to $R_w = 0.076$. Positions for the hydrogen atoms were calculated (C-H = 1.00 Å), and further isotropic refinement gave $R_w = 0.063$. An absorption correction was then applied by using an $8 \times 8 \times 8$ grid. Refinement with anisotropic thermal parameters for all non-hydrogen atoms gave the residuals in Table X. The largest peaks on the final difference map were all due to heavy-atom noise, being randomly oriented about the tungsten and antimony atoms at distances of 0.99-1.10 Å and 1.10-1.16 Å, respectively.

Structure Determination of 5. Crystals of 5 were grown at -40 °C as described above for 3c. Inspection of the data showed that reflections having 0k0, k = 2n + 1, and h0l, h + l = 2n + 1, were systematically absent, consistent only with space group $P2_1/n$. A correction for the 3.7% decay of the three standard reflections was applied. Positions and isotropic thermal parameters for the 18 non-hydrogen atoms refined as above to $R_w = 0.062$. An absorption correction was then applied by using an $8 \times 8 \times 8$ grid. Refinement with anisotropic thermal parameters for all non-hydrogen atoms was carried out. A difference map allowed the location of five hydrogen atoms on the three methyl carbons, and the positions of the remaining hydrogen atoms were calculated (P-C-H and $H-C-H = 109.5^{\circ}$). Final refinement of all non-hydrogen atoms using

anisotropic thermal parameters gave the residuals in Table X. The largest peaks on the final difference map were all due to heavy-atom noise, being randomly oriented about the tungsten atom at distances of 0.97-1.56 Å

Structure Determination of 6. Crystals of 6 were grown at -40 °C as described above for 3c. Inspection of the data showed that reflections having 0k0, k = 2n + 1, and h0l, h + l = 2n + 1, were systematically absent, consistent only with space group $P2_1/n$. A correction for the 2.5% decay of the three standard reflections was applied. Positions and isotropic thermal parameters for the 20 non-hydrogen atoms refined as above to $R_w = 0.103$. An absorption correction was then applied by using an $8 \times 8 \times 8$ grid. Refinement with anisotropic thermal parameters for the three heaviest atoms gave $R_w = 0.078$. A difference map was used to locate one hydrogen atom on each of the methyl groups, and the positions of the remaining hydrogen atoms were then calculated as above. Refinement of all non-hydrogen atoms using anisotropic thermal parameters gave the residuals in Table X. The largest peaks on the final difference map were all due to heavy-atom noise, being randomly oriented about the tungsten atom at distances of 0.09-1.16 Å.

Acknowledgment. We wish to thank Professor C. E. Strouse and Dr. C. B. Knobler for their help with the X-ray structure determinations, Professor K. N. Trueblood for assistance with his thermal motion analysis program, Professor J. W. Faller (Yale University) for helpful discussions, Andrew Fortney for providing a sample of 3b, and Peter Bonnesen for assistance with several ¹⁹F NMR spectra. Financial support was provided by the donors of the Petroleum Research Fund, administered by the American Chemical Society, and by the Chevron Research Co., the UCLA Committee on Research, and a Biomedical Research Support Grant.

Supplementary Material Available: Tables of full crystallographic data for 3b, 3c, 5, and 6, positional parameters, bond distances and angles, and temperature factors for 3c, 5, and 6, and input frequencies and output force constants for 13 compounds and details of the calculation of the Cotton-Kraihanzel force constants (25 pages); tables of structure factors for 3c, 5, and 6 (33 pages). The X-ray data for 3b is available as supplementary material to ref 15. Ordering information is given on any current masthead page.

Notes

Contribution from Dow Corning Corporation, Midland, Michigan 48686

A New Synthetic Route to Fluorodisilanes via Selective **Reduction of Halofluorodisilanes**

John J. D'Errico[†] and Kenneth G. Sharp*

Received September 7, 1988

Our primary interest in fluorodisilanes was as potential molecular precursors to amorphous silicon films^{1,2} containing hydrogen and fluorine. The use of fluorodisilanes for this purpose eliminates the need for precursor gas mixtures such as SiF₄/SiH₄.³ In addition, lower deposition temperatures are required when compared to the case for compounds such as SiF₂H₂.⁴

Several routes to fluorodisilanes have been reported. Mixtures of SiF_2HSiH_3 and SiF_3SiH_3 were generated from the reaction of $SiCl_2HSiH_3$ with SbF_3 .⁵ Fluorodisilane is obtained via the cleavage of Si-O or Si-N bonds in $(Si_2H_5)_2O$ or $(Si_2H_5)_3N$ by BF₃.^{6,7} Also, direct current ("ozonizer") plasma synthesis of the symmetrical disilanes 1,2-difluorodisilane and 1,1,2,2-tetrafluorodisilane via coupling reactions of the radicals derived from

the monosilanes SiH₃F and SiH₂F₂ has been reported.⁵ This route has the disadvantages of involving slow, low-yield reactions and the difficulty of preparing pure SiFH₃.⁸

This report describes the reactions of bromofluoro- or chlorofluorodisilanes with Me₃SnH. These reactions are characterized by the selective reduction of Si-Cl or Si-Br bonds without cleavage of Si-F or Si-Si bonds.

Experimental Section

Materials and Manipulations. All manipulations were conducted by using a recirculating drybox (N2 atmosphere), Schlenk techniques (Ar atmosphere), and a grease-free glass vacuum line (background pressure <10⁻⁴ Torr). Trimethyltin chloride, SbF₃, [(CH₃)₂CHCH₂]₂AlH (DI-BAL-H, Aldrich Chemical Co.), and VITRIDE (70% NaAlH₂(OCH₂-CH₂OCH₃)₂ in toluene, Hexcel Specialty Chemicals) were used as obtained. Trimethyltin hydride was prepared from the LiAlH₄ reduction

- Uesugi, T.; Hisanori, I.; Matsumura, H. Jpn. J. Appl. Phys., Part 1 1985, 24, 909.
- Sharp, K. G.; D'Errico, J. J. U.S. Patent 4762808, Aug 9, 1988. Drake, J. E.; Westwood, N. P. C. J. Chem. soc. A 1971, 3300.
- (5)
- (6)
- (7)
- Abedini, M.; MacDiarmid, A. G. Inorg. Chem. 1963, 2, 608. Aylett, B. J. Adv. Inorg. Chem. Radiochem. 1968, 11, 249. Ebsworth, E. A. V. Volatile Silicon Compounds; Pergamon Press: New (8)York, 1963; p 31.

[†] Present address: Indian Orchard Plant, Monsanto Chemical Co., Springfield, MA 01151.

⁽¹⁾ Stutzmann, M.; Jackson, W. B.; Tsai, C. C. J. Non-Cryst. Solids 1985, 77&78, 363

Janai, M.; Weil, R.; Pratt, B. Phys. Rev. B 1985, 31, 5311.

of Me₃SnCl.⁹ SiF₂HSiF₂Br was obtained from the reaction of SiF₂¹⁰ with HBr;¹¹ the redistribution of SiF₂HSiF₂Br yielded SiF₃SiF₂H, Si-F₃SiFHBr, and SiF₃SiHBr₂.¹¹ SiF₃SiHCl₂ and SiF₂HSiF₂Cl were obtained from the reaction of SnCl₄ with SiF₃SiHBr₂ and SiF₂HSiF₂Br, respectively.¹² Unless otherwise noted, reactions involving Me_3SnH were performed on a vacuum line in the absence of solvent. The tin byproduct of these reactions was shown to be Me₃SnX (X = Br, Cl) by ¹H NMR and IR spectroscopy.¹³ Me₃SnX was removed from the disilanes by passing the mixtures through a trap cooled to -95 °C (toluene), at which temperature the disilanes are volatile.

Spectral Measurements. The NMR tubes (5 mm o.d., wall thickness 0.77 mm) were flamed out under vacuum prior to loading. High-resolution ¹H and ¹⁹F NMR spectra (toluene- d_8) were obtained on a Varian XL200 spectrometer operating at 200 and 188 MHz, respectively. Infrared spectra (gas cell, KBr windows, 2-cm⁻¹ resolution) were obtained on a Nicolet 5SXB Fourier transform spectrometer.

Reduction of SiF₃SiHBr₂ Using VITRIDE (NaAlH₂(OCH₂CH₂OC- $H_3)_2$) or DIBAL-H (*i*-Bu₂AlH). The same procedure was used with each reducing agent. SiF₃SiHBr₂ (0.15 mmol) was condensed into a flask at -196 °C and then warmed to -78 °C (2-propanol/CO₂). The reducing agent (0.15 mmol, in 15 mL of toluene) was added in portions over 30 min; no volatile compounds could be removed under vacuum at this point. The mixture was warmed to room temperature for 15 min. The volatile compounds were then removed under vacuum; an IR spectrum indicated the presence of SiH₄ (40%), SiF₃H (40%), and SiF₄ (20%; yields estimated from IR measurements). There were no disilanes present in the mixture

Reduction of SiF₃SiHBr₂ Using LiAlH₄. SiF₃SiHBr₂ (0.2 mmol) and LiAlH₄ (0.2 mmol) were allowed to react at room temperature for 15 min. An IR spectrum of the volatile material indicated the presence of SiF₃H (45%), SiH₄ (45%), SiH₃SiH₃ (5%),¹⁴ and unreacted SiF₃SiHBr₂ (5%; yields estimated from IR measurements).

Reduction of SiF₃SiHX₂ (X = Br, Cl) Using Me₃SnH. SiF₃SiHBr₂ (0.2 mmol) and Me₃SnH (0.4 mmol) were warmed to room temperature for 30 min; IR spectra indicated that the SiF₃SiHBr₂ had been consumed. Pure SiF₃SiH₃, as determined from ¹H and ¹⁹F NMR and IR spectra,^{11,15} was isolated in 90% yield. Comparable results were obtained with Si-F₃SiHCl₂

SiF₃SiHBr₂, Me₃SnH, and CF₂=CF₂ (1:2:7 ratio) at -196 °C were warmed to room temperature for 10 min. An IR spectrum indicated the presence of only SiF₃SiH₃ and unreacted CF₂=CF₂.

One equivalent of SiF₃SiHCl₂ and 2 equiv of Me₃SnH were condensed into an NMR tube at -196 °C. No reaction was observed via ¹⁹F NMR as the tube was warmed to -10 °C for 25 min. The tube was then warmed to 0 °C and maintained at this temperature for 30 min. Very little SiF₃SiHCl₂ was observed in the mixture, the major component being SiF₃SiH₃. There were also small peaks due to SiF₃SiH₂Cl.¹² After 1 h at 0 °C, SiF₃SiHCl₂ and SiF₃SiH₂Cl were consumed, with the major product being SiF₃SiH₃ (90% yield).

Reaction of SiF₃SiFHBr with Me₃SnH. SiF₃SiFHBr (0.2 mmol) and Me₃SnH (0.2 mmol) were allowed to react at room temperature for 10 min. ¹H and ¹⁹F NMR and IR spectra indicated the presence of SiF₁- $SiF_2H^{11} \mbox{ and } SiF_3SiH_3 \mbox{ in approximately equimolar amounts (90% isolated } \label{eq:sifestimately}$ yield).

Equimolar quantities of SiF₃SiFHBr and Me₃SnH were condensed into a 5-mm medium-wall NMR tube at -196 °C. The mixture was warmed to -80 °C for 30 min. The ¹⁹F NMR spectrum contained peaks due to SiF₃SiFHBr (major), SiF₃SiH₃, SiF₃SiF₂H, and SiF₃SiHBr₂. A triplet centered at -122.9 ppm (relative to external CFCl₃) with ${}^{3}J_{H-F}$ = 7.7 Hz was also present. The mixture was gradually warmed to 10 °C; the major products were SiF_3SiH_3 and SiF_3SiF_2H (1:1 ratio, 90% yield), with small amounts of SiF₃SiFHBr and SiF₃SiHBr₂ remaining.

Reaction of SiF_2HSiF_2X (X = Br, Cl) with Me₃SnH. Equimolar quantities of SiF₂HSiF₂Br and Me₃SnH were allowed to react at room temperature for 10 min. An IR spectrum indicated the major products

- (9) (a) Dillard, C. R.; May, L. J. Mol. Spectrosc. 1964, 14, 250. (b) Maddox, M. L.; Flitcroft, N.; Kaesz, H. D. J. Organomet. Chem. 1965, 4, 50. (c) Potter, P. E.; Pratt, L.; Wilkinson, G. J. Chem. Soc. 1964, 524
- (10) (a) Margrave, J. L.; Sharp, K. G.; Wilson, P. W. Fortschr. Chem. Forsch. 1972, 26, 1. (b) Perry, D. L.; Margrave, J. L. J. Chem. Educ. 1976, 53, 696. (c) Margrave, J. L.; Wilson, P. W. Acc. Chem. Res. 1971, 4, 145.
- (11) Sharp, K. G.; Bald, J. F., Jr. Inorg. Chem. 1975, 14, 2553.
 (12) D'Errico, J. J.; Sharp, K. G. Main Group Met. Chem., in press.
 (13) (a) Neumann, W. P. The Organic Chemistry of Tin; Interscience: New
- York, 1970. (b) Kupchik, E. J. Organotin Compounds; Sawyer, A. K., Ed.; Marcel Dekker: New York, 1971.
 (14) Bethke, G. W.; Wilson, M. K. J. Chem. Phys. 1957, 26, 1107.
- (15) Solan, D.; Burg, A. B. Inorg. Chem. 1972, 11, 1253.

of the reaction to be SiF₃SiF₂H and SiF₃SiH₃ (2:1 ratio, 90% yield). There were also absorptions in the Si-H stretching region at 2214 and 2198 cm⁻¹. Similar results were observed for SiF_2HSiF_2Cl .

Equimolar quantities of SiF2HSiF2Br and Me3SnH were condensed into a 5-mm medium-wall NMR tube at -196 °C. The sample was gradually warmed to -40 °C and held there for 20 min. Peaks due to SiF₃SiF₂H, SiF₂HSiF₂H,⁵ SiF₃SiFHBr, SiF₃SiHBr₂, and SiF₂BrSiFH- Br^{11} were observed. Most of the SiF₂HSiF₂Br was gone after the mixture had been held at 10 °C for 20 min. After 30 min at 20 °C, the major products of the reaction were SiF₃SiF₂H and SiF₃SiH₃ (2:1 ratio, 85% yield), together with equimolar quantities of SiF₃SiHBr₂, SiF₃SiH₂Br, SiF₃SiFHBr, and SiF₂HSiF₂H.

Results and Discussion

Fluorodisilanes of the general formula $Si_2F_xH_{6-x}$ were desired as precursors for the deposition of amorphous silicon films containing both hydrogen and fluorine. Our approach to these compounds involved the initial synthesis of bromofluoro- or chlorofluorodisilanes and the subsequent selective conversion of Si-Br or Si-Cl into Si-H.

The reactions between SiF₃SiHBr₂ and various conventional reducing agents (LiAlH₄, VITRIDE (NaAlH₂(OCH₂CH₂OC- $(H_3)_2$), and DIBAL (*i*-Bu₂AlH)) resulted in the cleavage of the Si-Si bond and reduction of some Si-F bonds. Although Si- H_3SiH_3 was observed in the reactions with LiAlH₄, no evidence was obtained for the formation of fluorodisilanes.

The reaction between SiF_3SiHX_2 (X = Br, Cl) and Me_3SnH (1:2 molar ratio) proceeded smoothly at room temperature to yield SiF₃SiH₃ in 90% yield. There was no evidence for further reaction of SiF₃SiH₃ with Me₃SnH. A low-temperature ¹⁹F NMR experiment (where X = Cl) indicated that these reductions proceed in a stepwise manner, as evidenced by observation of SiF₃SiH₂Cl.¹² SiF₃SiH₃ has previously been observed as a member of a complex mixture of products resulting from the reaction of SiF_2 and $B_2\dot{H}_6$.¹⁵ A two-step separation process then had to be used to obtain pure SiF₃SiH₃.

The corresponding reaction of SiF₃SiFHBr with Me₃SnH was expected to provide the previously unknown molecule SiF₃SiFH₂. However, when equimolar amounts of SiF₃SiFHBr and Me₃SnH were allowed to react at room temperature, the products consisted of SiF_3SiF_2H and SiF_3SiH_3 in a 1:1 molar ratio (90% yield). There was no evidence of other disilanes in the product mixture. A possible explanation for this behavior is that SiF_3SiFH_2 is initially formed but that it quickly undergoes redistribution to give the observed products. Such behavior would parallel that of fluorosilane, which has been described as being very susceptible to F/H bond redistribution.⁸

Mechanistic insight into this reaction was provided by a lowtemperature ¹⁹F NMR experiment. SiF₃SiFHBr and Me₃SnH were condensed into an NMR tube at -196 °C and warmed to -80 °C for 30 min. An NMR spectrum obtained at this point indicated the presence of SiF₃SiFHBr, SiF₃SiH₃, SiF₃SiF₂H, and SiF₃SiHBr₂. A triplet centered at -122.9 ppm (relative to external CFCl₃) with ${}^{3}J_{H-F} = 7.7$ Hz is very similar to that observed for $SiF_3SiH_2Cl^{12}$ and is assigned to SiF_3SiH_2Br . There was no direct evidence for the formation of SiF₃SiFH₂ even at this low temperature. The presence of SiF₃SiHBr₂ indicates that the starting material undergoes F/Br redistribution reactions prior to reduction by the tin hydride (eq 1). SiF₃SiHBr₂ could then undergo stepwise

$$2SiF_{3}SiFHBr \rightarrow SiF_{3}SiF_{2}H + SiF_{3}SiHBr_{2}$$
(1)

reduction (via SiF₃SiH₂Br) to the observed SiF₃SiH₃.

In the absence of Me₃SnH, SiF₃SiFHBr requires several hours at room temperature to undergo redistribution to form SiF₃SiF₂H and SiF₃SiHBr₂. This observation suggests that Me₃SnH is promoting redistribution (eq 1), even at -80 °C. Conversion of Si-Br into Si-H by the tin hydrides occurs only after this redistribution has occurred.

The reaction between SiF₂HSiF₂Br and Me₃SnH was also investigated. An infrared spectrum of the products of a roomtemperature reaction indicated the presence of SiF_3SiF_2H and SiF₃SiH₃ (2:1 ratio, 90% yield). There was also an absorption in the Si-H stretching region at 2214 cm⁻¹; this feature is tentatively assigned to SiF₂BrSiFHBr, given the similarity of this

stretching frequency to that of SiF₃SiFHBr (2216 cm⁻¹). A second absorption at 2198 cm⁻¹ could be due to a compound such as SiF₃SiH₂Br, as this frequency lies between the Si-H stretches of SiF_3SiH_3 (2189 cm⁻¹) and SiF_3SiHBr_2 (2203 cm⁻¹).¹⁶

A low-temperature ¹⁹F NMR experiment revealed a rather complex series of reactions. As was the case for SiF₃SiFHBr, this reaction is characterized by the initial F/Br redistribution of the starting SiF₂HSiF₂Br. A complicating factor is the availability of both ends of SiF₂HSiF₂Br for redistribution (for SiF₃SiFHBr, SiF_3 is inert with respect to redistribution). The redistribution of SiF₂HSiF₂Br leads to the formation of SiF₃SiF₂H, SiF₂Br-SiFHBr, SiF₃SiFHBr, and SiF₃SiHBr₂.¹¹ Additionally, the direct reduction of the starting material to SiF₂HSiF₂H appears to proceed at a competitive rate, as a small amount of this compound was observed in the early stages of this reaction.

It was thought that the corresponding redistribution reactions would be slower for SiF₂HSiF₂Cl, thus allowing the isolation of SiF_2HSiF_2H . However, comparable results were obtained in the reactions of SiF2HSiF2Br or SiF2SiF2Cl with Me3SnH.

Organotin hydrides typically react with organic halides and unsaturated bonds via a free-radical mechanism. These reactions require heating, irradiation, or initiation by a free-radical source.¹⁷ However, in the case of the bromofluoro- or chlorofluorodisilanes, the reactions proceeded below room temperature and in the absence of free-radical initiators. There was no evidence of Si-Si bond cleavage or products attributable to coupling of free radicals. Additionally, the reaction of SiF₃SiHBr₂ with Me₃SnH was unaffected by the presence of $CF_2 = CF_2$; under free-radical conditions, products attributable to the addition of Me₃SnH to the olefin should be apparent.¹⁸ A mechanism that is consistent with these observations involves a four-centered transition state in which there is a pairwise exchange of atoms between the silicon and tin. This type of transition state has been postulated for other reductions involving Me₃SnH¹⁹ and for the F-Br exchange observed between disilane molecules.¹¹

Other reactions of alkyltin hydrides have been suggested to proceed via nucleophilic attack of the tin hydride, resulting in a polar transition state.²⁰ However, these reactions are promoted by the presence of polar solvents. Since the reactions involving halofluorodisilanes can occur in the gas phase, we do not feel that polar transition states play an important role in these reactions.

Conclusions

SiF₃SiH₃ is obtained in 90% yield from the reaction of SiF_3SiHX_2 (X = Br, Cl) with 2 equiv of Me₃SnH. F/Br redistribution precedes reduction in reactions between $SiF_3SiFHBr$ and Me₃SnH, resulting in mixtures of SiF₃SiF₂H and SiF₃SiH₃ (1:1 ratio, 90% yield). The reaction of SiF_2HSiF_2X (X = Br, Cl) with Me₃SnH also led to mixtures of SiF₃SiF₂H and SiF₃SiH₃ (2:1 ratio) in 85–90% yield; small amounts of SiF_2HSiF_2H (<5%) were also observed.

Acknowledgment. We wish to thank the Solar Energy Research Institute for support of this work through Contract No. ZL-5-04074-6.

Registry No. SiF₃SiHBr₂, 56144-86-6; NaAlH₂(OCH₂CH₂OCH₃)₂, 22722-98-1; *i*-Bu₂AlH, 1191-15-7; SiH₄, 7803-62-5; SiF₃H, 13465-71-9; SiF₄, 7783-61-1; LiAlH₄, 16853-85-3; SiH₃SiH₃, 1590-87-0; SiF₃SiHCl₂, 119895-84-0; Me₃SnH, 1631-73-8; CF₂==CF₂, 116-14-3; SiF₃SiH₂Cl, 121097-51-6; SiF₃SiFHBr, 56144-87-7; SiF₃SiF₂H, 24628-33-9; SiF₃-SiH₃, 15195-26-3; SiF₂HSiF₂Br, 51040-08-5; SiF₂HSiF₂Cl, 119895-86-2; SiF₂HSiF₂H, 34669-37-9; SiF₂BrSiFHBr, 56144-88-8; SiF₃SiH₂Br, 121097-52-7.

Contribution from the Chemistry Department, The Chinese University of Hong Kong, Shatin, NT, Hong Kong

Theoretical Study of the Structures, Relative Stabilities, and Infrared Spectra of the Isomeric NSO⁻ Anions

Suk Ping So

Received October 17, 1988

The potassium salt of the NSO⁻ anion was first prepared and characterized by vibrational spectroscopy about 10 years ago by Armitage and Brand.¹ They suggested that this anion be called the thiazate ion. However, the synthesis, spectroscopic data, and X-ray structure of the isovalent thionitrite anion SNO⁻ (as the $(Ph_2P)_2N^+$ salt) were reported only recently.²

To compare the structures, stabilities, and spectroscopic properties of the above two isomeric anions, Chivers et al.³ have carried out a calculation on their structures. They optimized the bond angles of NSO⁻ and SNO⁻ by the MNDO method, fixing the bond lengths at those for $(Ph_2P)_2N^+SNO^-$ obtained from X-ray diffraction analysis. Then a single-point ab initio calculation was done to compute the orbital eigenvalues and Mulliken's populations by using the double- ζ basis (i.e. each atomic orbital is represented by two basis functions) of Clementi and Roetti⁴ augmented with a 3d polarization function on sulfur (DZ+d(S)).⁵ In fact, the equilibrium geometries and relative stabilities of NSO⁻ and SNO⁻ have been computed earlier by Ehrhardt and Ahlrichs⁶ using the ab initio SCF method and basis sets of better than double- ζ plus polarization functions quality.

To the author's knowledge, the other isomeric anions SONand cyclic cy-NSO⁻ are still not known. In addition, infrared data for SNO⁻ are lacking. Hence, a theoretical study on the structures and infrared spectra of these four isomeric anions was carried out in the hope that this work may be helpful to their future experimental identification. The optimized geometries of NSO⁻ and SNO⁻, though reported earlier,⁶ were recalculated because it is more consistent to discuss and compare results of these anions obtained with the same basis set.

Calculations

The structures of NSO⁻, SNO⁻, SON⁻, and cy-NSO⁻ were fully optimized by the energy gradient method using the GAUSSIAN 82 and Gaussian 86 packages of programs.⁷ The standard 6-31G* and 6-31+-G* basis functions were used. (A 6-31G split-valence basis set utilizes the expansion of six Gaussian functions for each inner-shell atomic orbital and, for each valence atomic orbital, two valence shells comprising three and one Gaussian functions, respectively. A 6-31G* basis set results when a set of six d-type functions for the second-row atom is added.) The extra electron in an anion is usually weakly bound. Even large basis sets such as 6-31G* do not incorporate functions with significant amplitude at a distance from their center and thus do not provide a completely adequate description of molecular species in which a large portion of the valence electron density is allocated to diffuse lone-pair or to antibonding orbitals. One way to overcome problems associated with anion calculations is to include in the basis set one or more highly diffuse functions, such as the 6-31+G* set, which is the 6-31G* set augmented by a single set of diffuse Gaussian s- and p-type functions for each of the constituent atoms.⁸ These basis functions are then able to describe properly the

- (1) Armitage, D. A.; Brand, J. C. J. Chem. Soc., Chem. Commun. 1979, 1078
- Seel, F.; Kuhn, R.; Simon, G.; Wagner, M.; Krebs, B.; Dartmann, M. (2) Z. Naturforsch. 1985, 40B, 1607.
- (3)Chivers, T.; Silva, A. B. F. D.; Treu, O., Jr.; Trsic, M. J. Mol. Struct. 1987, 162, 351

- (4) Clementi, E.; Roetti, A. At. Data Nucl. Data Tables 1974, 14, 177.
 (5) Laidlaw, W. G.; Trsic, M. Chem. Phys. 1979, 36, 323.
 (6) Ehrhardt, C.; Ahlrichs, R. Chem. Phys. 1986, 108, 417.
 (7) (a) Binkley, J. S.; Frisch, M. J.; DeFrees, D. J.; Raghavachari, K.; Whiteside, R. A.; Schlegel, H. B.; Fluder, E. M.; Pople, J. A. "GAUSSIAN 82"; Carnegie-Mellon University: Pittsburgh, PA, 1983.
 (b) Erisch, M. J.; Bickley, L. S.; Schlegel, H. B.; Pachyacabari, K.; (b) Frisch, M. J.; Binkely, J. S.; Schlegel, H. B.; Raghavachari, K.; Melius, C. F.; Seeger, R.; Whiteside, R. A.; Fox, D. J.; Fleuder, E. M.; Pople, J. A. "Gaussian 86"; Carnegie-Mellon Quantum Chemistry Publishing Unit: Pittsburgh PA, 1984.

Excellent correlations between Si-H stretching frequencies and the functionality on silicon have been observed. See: Smith, A. L. In (16)Chemical, Biological and Industrial Applications of Infrared Spectroscopy; Durig, J. R., Ed.; Wiley-Interscience: New York, 1985. Kuivila, H. G. Synthesis 1970, 499. (17)

 ⁽¹⁸⁾ Clark, H. C.; Furnival, S. G.; Kwon, J. T. Can. J. Chem. 1963, 41, 2889.
 (19) Dehnert, P.; Grobe, J.; Le Van, D. Z. Naturforsch. 1981, 36B, 48.
 (20) (a) Gaines, D. F.; Kunz, J. C.; Kulzick, M. J. Inorg. Chem. 1985, 24,

^{3336. (}b) Emery, S. L.; Morrison, J. A. Inorg. Chem. 1985, 24, 1613. (c) Leusink, A. J.; Marsman, J. W. Recl. Trav. Chim. Pays-Bas 1965, 84, 1123.